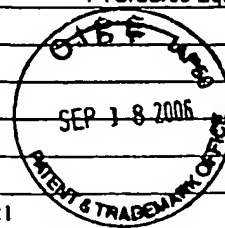


# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Multiple sheets used when necessary)

SHEET 1 OF 6

Application No.	10/810,660
Filing Date	March 29, 2004
First Named Inventor	Wen-Jian Lin
Art Unit	2823
Examiner	Jarrett J. Stark
Attorney Docket No.	QCO.091A/061121



## U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
JS	1	3,616,312	10/26/1971	McGriff et al.	
	2	4,392,711	07/12/1983	Moraw et al.	
	3	4,617,608	10/14/1986	Blonder, et al.	
	4	4,859,060	08/22/1989	Kitagiri et al.	
	5	4,900,136	02/13/1990	Goldburt et al.	
	6	4,900,395	02/13/1990	Syversen et al.	
	7	4,965,562	10/23/1990	Verhulst	
	8	5,212,582	05/18/1993	Nelson	
	9	5,293,272	03/08/1994	Jannson et al.	
	10	5,330,617	07/19/1994	Michael Haond	
	11	5,347,377	09/13/1994	Revelli Jr. et al.	
	12	5,355,357	10/25/1994	Yamamori et al.	
	13	5,358,601	10/25/1994	Cathey	
	14	5,474,865	12/12/1995	Vasudev	
	15	5,499,037	03/12/1996	Nakagawa et al.	
	16	5,647,819	07/15/1997	Fujita, et al.	
	17	5,650,834	07/22/1997	Nakagawa et al.	
	18	5,822,170	10/13/1998	Cabuz et al.	
	19	5,824,608	10/20/1998	Gotoch, et al.	
	20	5,838,484	11/17/1998	Goosen, et al.	
	21	6,016,693	01/25/2000	Viani et al.	
	22	6,057,903	05/02/2000	Colgan et al.	
	23	6,158,156	12/12/2000	Patrick, David	
	24	6,166,422	12/26/2000	Qian et al.	
	25	6,194,323	02/27/2001	Downey et al.	
	26	6,204,080	03/20/2001	Hwang	
	27	6,246,398	06/12/2001	Koo	
	28	6,249,039	06/19/2001	Harvey et al.	
	29	6,327,071	12/04/2001	Kimura et al.	

Examiner Signature

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Date Considered 10/11/2006

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U.S. PATENT DOCUMENTS					
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JS	30	6,329,297	12/11/2001	Balish et al.	
	31	6,335,831	01/01/2002	Kowarz et al.	
	32	6,391,675	05/21/2002	Ehmke et al.	
	33	6,392,781	05/21/2002	Kim et al.	
	34	6,522,801	02/18/2003	Aksyuk et al.	
	35	6,531,945	03/11/2003	Ahn et al.	
	36	6,537,427	03/25/2003	Raina et al.	
	37	6,577,785	06/10/2003	Spahn et al.	
	38	6,610,440	08/26/2003	LaFollette et al.	
	39	6,642,913	11/04/2003	Kimura et al.	
	40	6,674,033	01/06/2004	Chui et al.	
	41	6,687,896	03/15/2004	Miles	
	42	6,756,317	06/29/2004	Sniegowski, et al.	
	43	6,768,097	07/27/2004	Viktorovitch et al.	
	44	6,775,174	08/10/04	Huffman et al.	
	45	6,778,155	08/17/04	Doherty et al.	
	46	6,778,306	08/17/04	Sniegowski, et al.	
	47	6,794,119	09/21/04	Miles	
	48	6,811,267	11/02/04	Allen et al.	
	49	6,812,482	11-02-2004	Fleming, et al.	
	50	6,819,469	11/16/04	Koba	
	51	6,822,628	11/23/04	Dunphy et al.	
	52	6,829,132	12/07/04	Martin et al.	
	53	6,853,129	02/08/05	Cummings et al.	
	54	6,855,610	02/15/05	Tung et al.	
	55	6,859,218	02/22/05	Luman et al.	
	56	6,861,277	03/01/05	Monroe et al.	
	57	6,862,022	03/01/05	Slupe	
	58	6,862,029	03/01/05	D'Souza et al.	

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U.S. PATENT DOCUMENTS					
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JS	59	6,867,896	03/15/05	Miles	
	60	6,870,581	03/22/05	Li et al.	
	61	6,870,654	03/22/05	Lin et al.	
	62	6,882,458	04/19/05	Lin et al.	
	63	6,882,461	04/19/05	Tsai et al.	
	64	6,905,621	06-14-2005	Ho et al.	
	65	6,912,022	06/28/05	Lin et al.	
	66	6,952,303	10/04/05	Lin et al.	
	67	6,952,304	10-04-2005	Mushika et al.	
	68	6,958,847	10/25/05	Lin	
	69	6,980,350	12/27/2005	Hung et al.	
	70	6,982,820	01/03/2006	Tsai	
	71	6,995,890	02/07/2006	Lin	
	72	6,999,225	02/14/2006	Lin	
	73	6,999,236	02/14/2006	Lin	
	74	2002-0086455	07/04/2002	Franosch et al.	
	75	2002-021485	02/21/2002	Pilossof	
	76	2002-024711	02/28/2002	Miles	
	77	2002-0075555	06-20-2002	Miles	
	78	2002-149828	10/17/2002	Miles	
	79	2003-0054588	03/20/2003	Patel, et al.	
	80	2003-201784	10/30/2003	Potter	
	81	2003-0231373	12/18/2003	Kowarz et al.	
	82	2004-0058531	03/25/2004	Miles et al.	
	83	2004-0125536	07/01/2004	Arney et al.	
	84	2004-0124073	07-01-2004	Pilans et al.	
	85	2004-0148009	07/29/2004	Buzzard	
	86	2004-0179445	09/16/2004	Park	
JS	87	2004-0087086	05/06/2004	Lee	

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U.S. PATENT DOCUMENTS					
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JS	88	2005-0195467	09/08/2005	Kothari et al.	
JS	89	2006-0066932	05/30/2006	Chui	

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T <sup>1</sup>
JS	90	CH 681 047	12-31-1992	Landis & GYR Betriebs		
	91	CN 092109265	11/19/2003	Lin		
	92	DE 10228946 A1	01-22-2004	Universitat Bremen		
	93	EP 0173808	03/12/1986	Deutsche Thomson-Brandt		
	94	EP 0 667 548 A1	08-16-1995	AT&T Corporation		
	95	EP 0878824A 2	11-18-1998	Surface Tech. Systems		
	96	EP 1258860 A1	11/20/2002	Eastman Kodak Company		
	97	JP 10-148644	06/02/1998	TDK Corp		
	98	JP 10-267658	10/09/1998	Nissan Motor Corp.		
	99	JP 10500224	01/06/1998			
	100	JP 11211999 A	08/06/1999	Teijin Ltd.		
	101	JP 11243214	09/07/1999	Nippon Telegr & Teleph	Abstract Only	
	102	JP 2000-40831A	02/08/2000	Denso Corp	Abstract Only	
	103	JP 2002-270575	09/02/2002	Seiko Epson Corp.		
	104	JP 2002-355800	12/10/2002	Samsung Electronics	Abstract Only	
	105	JP 2004-102022A	04/02/2004	Ricoh Co. Ltd.	Abstract Only	
	106	JP 2004-212656	07/29/2004	Fuji Photo Film	Abstract Only	
	107	KR 2000-0033006	06/15/2000	Moon et al.		
	108	KR 2002-9270	10/23/1999			
	109	RCO Pt Pub 157313	05/01/1991	FSI International		
	110	WO 05/085932A	09/15/2005	Kothari et al.		
	111	WO 06/036385	04/06/2006	IDC, LLC		
JS	112	WO 06/036437	04/06/2006	IDC, LLC		

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JS	113	WO06/036542	04/06/2002	IDC, LLC		
JS	114	WO 92/10925	06/25/1992	Robert Bosch GmbH		

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>1</sup>
JS	115	Austrian Search Report for EX72/2005 dated May 13, 2005.	
	116	Austrian Search Report for EX81/2005 dated May 18, 2005.	
	117	Austrian Search Report for EX170/2005 dated July 6, 2005.	
	118	Austrian Search Report for EX139/2005 dated July 27, 2005.	
	119	Austrian Search Report for EX144/2005 dated August 11, 2005.	
	120	BAINS, "Digital Paper Display Technology Holds Promise For Portables," CommsDesign EE Times (2000).	
	121	BASS, "Handbook of Optics, volume 1, Fundamentals, Techniques, and Design, Second Edition, McGraw-Hill, inc. New York pp. 2.29/2.36 (1995).	
	122	CHU, et al. "Formation and Microstructures of Anodic Alumina Films from Aluminum Sputtered on glass Substrate" Journal of the Electrochemical Society, 149 (7) B321-B327 (2002).	
	123	CROUSE, "Self-ordered pore structure of anodized aluminum on silicon and pattern transfer" Applied Physics Letters, volume 76, Number 1, January 3, 2000. pps 49-51.	
	124	FRENCH, P.J. "Development of Surface Micromachining techniques compatible with on-chip electronics" Journal of Micromechanics and Microengineering vol 6 No. 2, 197-211 XP 002360789 June (1996) IOP Publishing.	
	125	FURNEAUX, et al. "The Formation of Controlled-porosity membranes from Anodically Oxidized Aluminium" Nature vol 337 12 January 1989, pp. 147-149.	
	126	JERMAN J. H. ET AL., "MANIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM SYSTEMS," Transducers. San Francisco, June 24-27, 1991, Proceedings of the International Conference on Solid State Sensors and Actuators, New York IEEE, US, vol. Conf. 6, June 24, 1991.	
	127	LIEBERMAN, "MEMS Display Looks to Give PDAs Sharper Image," EE Times (February 11, 1997).	
JS	128	LIEBERMAN, "Microbridges at Heart of New MEMS Displays," EE Times (April 24, 1997).	

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JS	129	MABOUDIAN, et al. "Critical Review: Adhesion in Surface Micromechanical Structures: J. Vac. Sci Techno. B 15(1) Jan/Feb 1997, pps. 1-20.	
	130	MICROCHEM, LOR Lift-Off Resists Datasheet, 2002.	
	131	MILES, "Interferometric Modulation: MOEMS as an Enabling Technology for High-Performance Reflective Displays," Proceedings of the International Society for Optical Engineering, San Jose, CA, Vol. 49085, pp. 131-139 (January 28, 2003).	
	132	Miles, et al., "10.1: Digital Paper for Reflective Displays," 2002 SID International Symposium Digest of Technical Papers, Boston, MA, SID International Symposium Digest of Technical Papers, San Jose, CA, Vol. 33 / 1, pp. 115-117 (May 21-23, 2002).	
	133	Penta Vacuum MEMS Etcher Specifications, <a href="http://www.pentavacuum.com/memes.htm">http://www.pentavacuum.com/memes.htm</a> .	
	134	Science and Technology, The Economist, pp. 89-90, (May 1999).	
	135	Search Report PCT/US05/030033 and Written Opinion.	
	136	Search Report PCT/US05/030902.	
	137	Search Report and Written Opinion for PCT/US05/33558 (05/19/2005).	
	138	Search Report PCT/US05/032331 (04/07/06)	
	139	Search Report PCT/US05/032331 (01/09/06)	
	140	Search Report and written opinion PCT/US05/032647	
	141	TAYEBI et al. "Reducing the Effects of adhesion and friction in microelectromechanical systems (MEMS) through surface roughening: Comparison Between theory and experiments" <a href="http://jap.aip.org/jap/copyright.jsp">http://jap.aip.org/jap/copyright.jsp</a> Journal of applied Physics 98, 073528 (2005).	
	142	Thin Film Transistors- Materials and Processes -Volume1 Amorphous Silicon Thin Film Transistors" ed. Yue Kuo, Kluwer Academic Publishers, Boston (2004).	
	143	Xactix Xetch X Specifications, <a href="http://xactix.com/Xtech X3specs.htm">http://xactix.com/Xtech X3specs.htm</a> . January 5, 2005	
JS	144	Xactix Xetch Product information.	

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